L Number	Hits	Search Text	DB	Time stamp
1	348	73/204.26.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/23 16:08
2	155	73/204.15.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/23 16:05
3	124	73/204.18.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/23 16:05
4	348	73/204.26.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/23 16:05
5	83	73/204.16.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/23 16:06
7	73	73/204.24.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/23 16:07
8	105	73/204.23.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/23 16:21
9	44	(73/204.26.ccls. 73/204.15.ccls. 73/204.18.ccls. 73/204.26.ccls. 73/204.16.ccls. ((73/204).CCLS.) 73/204.24.ccls. 73/204.23.ccls.) and ((frame structure base layer film) near4 silicon$2) and ((heat$4 therm$5) near5 (frame structure base layer film)) and ((frame structure base layer film) near4 (thermometer temperature) near4 (measur$4 meter$4 determin$4 detect$4 asses$4))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/23 16:51
-	279	73/204.26.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/23 16:04
-	9	("5423212" "5393351" "5703287").pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/01/24 17:06
-	200	73/204.26.ccls. and (membrane coat$4 layer)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/01/24 17:19
-	1	73/204.26.ccls. and (membrane coat$4 layer) and impermeable	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/01/24 17:19
-	2	("4682503" | "4766666").PN.	USPAT	2002/01/24 17:20

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-	27	4766666.URPN.	USPAT	2002/01/24 17:20
-	64	73/204.26.ccls. and silicon and nitride	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/01/24 18:05
-	58	73/204.26.ccls. and silicon and nitride and (heat$4 therm$5) and (insulat$5 imperm$6 membrane)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/01/24 18:20
-	55	73/204.26.ccls. and silicon and nitride and (heat$4 therm$5) and (insulat$5 imperm$6 membrane) and (temperat$5 near2 (sens$4 measur$6))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/25 15:21
-	17	73/204.26.ccls. and silicon and nitride and (heat$4 therm$5) and (insulat$5 imperm$6 seal$5) and membrane and (temperat$5 near2 (sens$4 measur$6))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/01/24 19:03
-	15	73/204.26.ccls. and silicon and nitride and (heat$4 therm$5) and (insulat$5 imperm$6 seal$5) and membrane and (temperat$5 near2 (sens$4 measur$6)) and (contact terminal)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/01/24 20:35
-	14	73/204.26.ccls. and silicon and nitride and (heat$4 therm$5) and (insulat$5 imperm$6 seal$5) and membrane and (temperat$5 near2 sens$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/07/14 14:20
-	3	73/204.26.ccls. and carbide	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/01/24 20:36
-	25	("5393351" "5852239" "5423212" "5703287" "6318170" "6290388" "6240777" "5965813" "4682503" "4545650").pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/01/25 10:42
-	4	(("si.sub.3.n.sub.4.") or (silicon? near2 nitride)) and (heat$4 therm$5) and ((no? near3 permea$4) imperm$6) and (temperat$5 near2 (sens$4 detect$4 determin$4 meter$4 measur$6))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/25 15:44
-	0	"si.sub.3.n.sub.4."	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/25 15:46
-	1	"si.sub.3-n.sub.4"	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/25 15:49
-	17387	"si.sub.3 n.sub.4"	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/25 15:49

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-	51	("si.sub.3 n.sub.4" or (silicon? near2 nitride)) and ((no? near3 permea$4) imperm$6) and (temperat$5 near2 (sens$4 detect$4 determin$4 meter$4 measur$6))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/25 16:52
-	4	("si.sub.3 n.sub.4" or (silicon? near2 nitride)) same ((no? near3 permea$4) imperm$6) and (temperat$5 near2 (sens$4 detect$4 determin$4 meter$4 measur$6))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/25 15:58
-	6	("si.sub.3 n.sub.4" or (silicon? near2 nitride)) same ((no? near3 permea$4) imperm$6) and ((temperat$5 heat) near2 (sens$4 detect$4 determin$4 meter$4 measur$6))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/25 16:19
-	64	("si.sub.3 n.sub.4" or (silicon? near2 nitride)) and ((water near2 repel$5) or (no? near3 permea$4) or impermea$6) and (temperat$5 near2 (sens$4 detect$4 determin$4 meter$4 measur$6))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/25 16:15
-	17	(("si.sub.3 n.sub.4" or (silicon? near2 nitride)) and ((water near2 repel$5) or (no? near3 permea$4) or impermea$6) and (temperat$5 near2 (sens$4 detect$4 determin$4 meter$4 measur$6))) and sandw$6	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/25 16:15
-	17	("si o.sub.2" or (silicon? near2 oxide)) near6 (recess hole hollow cavity gap)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/25 16:54
-	553	((frame structure base layer film) near4 silicon$2) and (silicon$2 near4 nitride) and (heat$4 therm$5) and (insulat$5 imperm$6 seal$5) and (diaphragm membrane) and (((temperat$5 heat thermal) near2 sens$4) or thermometer)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/07/14 14:52
-	332	(((frame structure base layer film) near4 silicon$2) and (silicon$2 near4 nitride) and (heat$4 therm$5) and (insulat$5 imperm$6 seal$5) and (diaphragm membrane) and (((temperat$5 heat thermal) near2 sens$4) or thermometer)) and ((sens$4 measur$4 determin$4 estimat$4 detect$4) near4 (flow volume mass))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/07/14 15:13
-	95	((((frame structure base layer film) near4 silicon$2) and (silicon$2 near4 nitride) and (heat$4 therm$5) and (insulat$5 imperm$6 seal$5) and (diaphragm membrane) and (((temperat$5 heat thermal) near2 sens$4) or thermometer)) and ((sens$4 measur$4 determin$4 estimat$4 detect$4) near4 (flow volume mass))) and 73/$6.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/23 16:22
-	4	("5965811" "5237867").pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/07/15 13:18